## REMARKS

In response to the Board of Appeals decision dated March 17, 2011, Applicants are filing this request for continued examination in which the mirrored surface is limited to a silicon wafer on which a tantalum nitride film is formed. Support for this amendment is found in paragraph [0032] of the specification. In the Board's decision, the Board stated that the evidence of unobvious results is not commensurate in scope with the claims and that only a silicon wafer having a tantalum nitride film was tested. Accordingly, the currently presented claims have been limited to this feature. A person of ordinary skill in the art would not come up with the present invention from the Kondo reference because Kondo fails to teach the use of a plating of a silicon wafer on which a tantalum nitride film is formed and there is no quarantee that the teaching of Imori, if applied to Kondo, would result in a successful plating operation. Favorable consideration of the present application is respectfully solicited.

Respectfully submitted,

Terryence F. Chapman

TFC/smd

FLYNN, THIEL, BOUTELL Terryence F. Chapman Reg. No. 32 549 & TANIS, P.C. Liane L. Churney Reg. No. 40 694 2026 Rambling Road Kalamazoo, MI 49008-1631 Brian R. Tumm Reg. No. 36 328 Heon Jekal Reg. No. 64 219 Phone: (269) 381-1156 Eugene J. Rath III Reg. No. 42 094 Fax: (269) 381-5465 Dale H. Thiel Reg. No. 24 323 David G. Boutell Reg. No. 25 072 Sidney B. Williams, Jr. Reg. No. 24 949

Encl: None

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